



PATENT #4

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January 16, 2002

Date

Rena Iov

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Ulrich C. Boettiger and Scott L. Light
Application No. : 09/945,316 Confirmation No.: 1351
Filed : August 30, 2001
For : METHOD AND APPARATUS FOR CONTROLLING RADIATION
BEAM INTENSITY DIRECTED TO MICROLITHOGRAPHIC
SUBSTRATES

Art Unit : 1756
Docket No. : 108298547US
Date : January 16, 2002

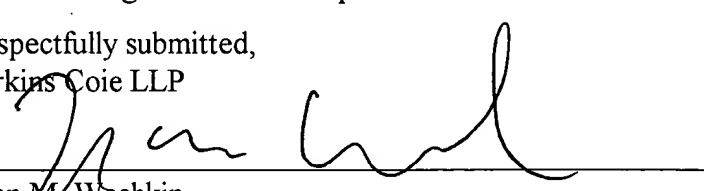
Commissioner for Patents
Washington, DC 20231

PETITION FOR EXTENSION OF TIME UNDER 37 CFR. § 1.136(a)

Sir:

Applicants herewith petition the Commissioner of Patents under 37 CFR § 1.136(a) for a one-month extension of time for filing the response to the Examiner's Action dated October 16, 2001, from December 16, 2001, to January 16, 2002, and enclose the amount of \$110.00 for the requisite fee. Any deficiency or overpayment should be charged or credited to Deposit Account No. 50-0665. This petition is being submitted in triplicate.

Respectfully submitted,
Perkins Coie LLP


John M. Wechkin
Registration No. 42,216

P.O. Box 1247
Seattle, Washington 98111-1247
(206) 583-8888
Fax: (206) 583-8500

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